

Title	Resonance assisted jump-in voltage reduction for electrostatically actuated nanobeam-based gateless NEM switches.
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Publication date	2019-07-08
Original Citation	Meija, R., Livshits, A. I., Kosmaca, J., Jasulaneca, L., Andzane, J., Biswas, S., Holmes, J. D. and Erts, D. (2019) 'Resonance assisted jump-in voltage reduction for electrostatically actuated nanobeam-based gateless NEM switches', Nanotechnology, 30(38), 385203 (6 pp). doi: 10.1088/1361-6528/ab2b11
Type of publication	Article (peer-reviewed)
Link to publisher's version	https://iopscience.iop.org/article/10.1088/1361-6528/ab2b11 - 10.1088/1361-6528/ab2b11
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Download date	2025-05-06 09:40:49
Item downloaded from	https://hdl.handle.net/10468/8213



## **Supplementary information**

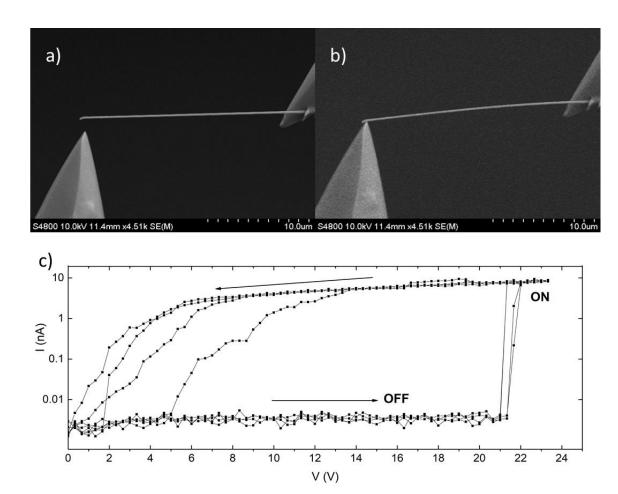


Figure 1. Additional NEM device with repeated measurements for GeSn nanowire with L = 22  $\mu$ m, d = 125 nm. a) – nanowire in an OFF state; b) – nanowire in ON state, c) – repeated IV measurements of NEM device. The AC assisted jump in occurred at 5 V + 0.6 V DC + AC voltage.